	Type	Hits	Search Text	DBs	Tim Stamp
1	BRS	50244	photolithograph$2	USPAT; EPO; JPO; IBM_TDB	2002/05/14 11:41
2	BRS	11955	photolithograph$2 WITH (IC OR integrated ADJ circuit OR semiconductor OR wafer)	USPAT; EPO; JPO; IBM_TDB	2002/05/14 11:43
3	BRS	305	(photolithograph$2 WITH (IC OR integrated ADJ circuit OR semiconductor OR wafer)) WITH control$4	USPAT; EPO; JPO; IBM_TDB	2002/05/14 11:44
4	BRS	17	((photolithograph$2 WITH (IC OR integrated ADJ circuit OR semiconductor OR wafer)) WITH control$4) SAME (barcode OR bar ADJ code OR scan$4)	USPAT; EPO; JPO; IBM_TDB	2002/05/14 11:45

05/14/2002, EAST Version: 1.03.0002

L #	Hits	Search Text	DBs	Time Stamp	Type
1	L7	7	("4636634" | "4833306" | "5314564" | "5567927" | "5814829" | "5933220" | "5953579").PN.	USPAT	2002/05/14 13:25	BRS
2	L8	11	5567927.URPN.	USPAT	2002/05/14 13:38	BRS
3	L9	8	("5175774" | "5265170" | "5329090" | "5511005" | "5567927" | "5877064" | "5877899" | "5942763").PN.	USPAT	2002/05/14 14:17	BRS
4	L10	2	5883374.URPN.	USPAT	2002/05/14 14:59	BRS
5	L11	1	5864130.URPN.	USPAT	2002/05/14 14:59	BRS
6	L12	28	4833306.URPN.	USPAT	2002/05/14 15:02	BRS
7	L13	0	6136614.URPN.	USPAT	2002/05/14 15:06	BRS
8	L14	7	5570293.URPN.	USPAT	2002/05/14 15:12	BRS

	1 [1]	Document ID	Source	Issue Date	Titl	Curr nt OR	Inventor	2
1	☒	US 6388253 B1	USPAT	20020514	Integrated critical dimension control for semiconductor device manufacturing	250/310	Su, Bo	☐
2	☒	US 5567927 A	USPAT	19961022	Apparatus for semiconductor wafer identification	235/462.01	Kahn, Randolph W. et al.	☒
3	☒	US 6147321 A	USPAT	20001114	Configuration for the automatic inscription or reinscription of wafers	219/121.68	Marx, Eckhard et al.	☒
4	☒	US 6136614 A	USPAT	20001024	Apparatus and method for manufacturing integrated circuit devices	438/5	Funk, Kevin K.	☐
5	☒	US 5883374 A	USPAT	19990316	Scanning system for identifying wafers in semiconductor process tool chambers	235/462.15	Mathews, Charles Ray	☒
6	☒	US 6265684 B1	USPAT	20010724	Wafer ID optical sorting system	209/583	Wu, Joseph	☒
7	☒	US 5864130 A	USPAT	19990126	Apparatus for semiconductor wafer identification	235/462.01	Kahn, Randolph W. et al.	☐
8	☒	US 4833306 A	USPAT	19890523	Bar code remote recognition system for process carriers of wafer disks	235/375	Milbrett, Lynn	☐
9	☒	US 6164530 A	USPAT	20001226	Disk carrier with transponder	235/380	Cheesebrow, Nicholas T. et al.	☐
10	☒	US 6138058 A	USPAT	20001024	Method for electronically tracking containers to avoid misprocessing of contents	700/225	Van Antwerp, Jr., Kenneth D. et al.	☒
11	☒	US 5742238 A	USPAT	19980421	System for communication between a central controller and items in a factory using infrared light	340/825.49	Fox, Christopher Wayne	☐
12	☒	US 5570293 A	USPAT	19961029	Method and device for manufacturing a semiconductor chip	700/121	Tanaka, Toshiyuki et al.	☒
13	☒	US 6112130 A	USPAT	20000829	Semiconductor product manufacturing execution system and semiconductor product manufacturing method	700/121	Fukuda, Etsuo et al.	☐

	L #	Hits	Search Text	DBs	Time Stamp	Type
1	L1	11605	(IC OR integrated ADJ circuit OR semiconductor OR wafer) WITH (manufactur$3 OR fabricat$3) WITH control$4	USPAT; EPO; JPO; IBM_TDB	2002/05/15 15:03	BRS
2	L2	442	L1 SAME display$3	USPAT; EPO; JPO; IBM_TDB	2002/05/15 15:04	BRS
3	L3	26	L2 SAME (barcode OR bar ADJ code OR scan$4)	USPAT; EPO; JPO; IBM_TDB	2002/05/15 15:26	BRS
4	L4	0	5942739.URPN.	USPAT	2002/05/15 15:10	BRS
5	L5	0	5828989.URPN.	USPAT	2002/05/15 15:14	BRS
6	L6	22	L2 SAME (reticle OR recipe)	USPAT; EPO; JPO; IBM_TDB	2002/05/15 15:28	BRS
7	L7	3	5740052.URPN.	USPAT	2002/05/15 15:35	BRS
8	L8	87	L2 SAME (track$3 OR monitor$3 OR identify$3 OR identification$1 OR sens$3)	USPAT; EPO; JPO; IBM_TDB	2002/05/15 15:46	BRS
9	L9	2	("5923553" | "6000830").PN.	USPAT	2002/05/15 15:47	BRS
10	L10	8	6000830.URPN.	USPAT	2002/05/15 15:49	BRS

	1 [1]	Document ID	Source	Issue Date	Title	Current OR	Inventor	2
1	☒	US 5942739 A	USPAT	19990824	Process timer monitor	235/462.01	Zvonar, John G. et al.	☒
2	☒	US 5828989 A	USPAT	19981027	Semiconductor manufacturing system having a bar-code interface	702/188	Zvonar, John G. et al.	☒
3	☒	US 6383402 B1	USPAT	20020507	Method and apparatus for monitoring plasma processing operations	216/60	Smith, Jr., Michael Lane et al.	☐
4	☒	US 6275740 B1	USPAT	20010814	Method and apparatus for monitoring plasma processing operations	700/108	Smith, Jr., Michael Lane et al.	☐
5	☒	US 6269278 B1	USPAT	20010731	Method and apparatus for monitoring plasma processing operations	700/121	Smith, Jr., Michael Lane et al.	☐
6	☒	US 6261470 B1	USPAT	20010717	Method and apparatus for monitoring plasma processing operations	216/60	Smith, Jr., Michael Lane et al.	☐
7	☒	US 6254717 B1	USPAT	20010703	Method and apparatus for monitoring plasma processing operations	156/345.24	Smith, Jr., Michael Lane et al.	☐
8	☒	US 6246473 B1	USPAT	20010612	Method and apparatus for monitoring plasma processing operations	356/316	Smith, Jr., Michael Lane et al.	☐
9	☒	US 6223755 B1	USPAT	20010501	Method and apparatus for monitoring plasma processing operations	134/1.1	Smith, Jr., Michael Lane et al.	☐
10	☒	US 6221679 B1	USPAT	20010424	Method and apparatus for monitoring plasma processing operations	438/7	Smith, Jr., Michael Lane et al.	☐
11	☒	US 6192826 B1	USPAT	20010227	Method and apparatus for monitoring plasma processing operations	118/723AN	Smith, Jr., Michael Lane et al.	☐
12	☒	US 6169933 B1	USPAT	20010102	Method and apparatus for monitoring plasma processing operations	700/121	Smith, Jr., Michael Lane et al.	☐
13	☒	US 6165312 A	USPAT	20001226	Method and apparatus for monitoring plasma processing operations	156/345.24	Smith, Jr., Michael Lane et al.	☐
14	☒	US 6157447 A	USPAT	20001205	Method and apparatus for monitoring plasma processing operations	356/316	Smith, Jr., Michael Lane et al.	☐
15	☒	US 6134005 A	USPAT	20001017	Method and apparatus for monitoring plasma processing operations	356/451	Smith, Jr., Michael Lane et al.	☐
16	☒	US 6132577 A	USPAT	20001017	Method and apparatus for monitoring plasma processing operations	204/298.32	Smith, Jr., Michael Lane et al.	☐
17	☒	US 6123983 A	USPAT	20000926	Method and apparatus for monitoring plasma processing operations	427/10	Smith, Jr., Michael Lane et al.	☐
18	☒	US 6090302 A	USPAT	20000718	Method and apparatus for monitoring plasma processing operations	216/60	Smith, Jr., Michael Lane et al.	☐
19	☒	US 6077386 A	USPAT	20000620	Method and apparatus for monitoring plasma processing operations	156/345.24	Smith, Jr., Michael Lane et al.	☐
20	☒	US 5740052 A	USPAT	19980414	Method and apparatus for manufacture of semiconductor devices	700/121	Nakamura, Gen	☒
21	☒	JP 10135092 A	JPO	19980522	OPERATION SITUATION DISPLAY DEVICE FOR SEMICONDUCTOR MANUFACTURING SYSTEM		YOSHIDA, YASUSHI	☒

	1 [1]	Document ID	Source	Issue Date	Title	Current OR	Inventor	2
22	☒	US 6000830 A	USPAT	19991214	System for applying recipe of semiconductor manufacturing apparatus	700/121	Asano, Atsushi et al.	☒
23	☒	US 6148246 A	USPAT	20001114	Semiconductor process system, its control method, computer readable memory, and device manufacturing method	700/121	Kawazome, Takeshi	☐
24	☒	US 6148244 A	USPAT	20001114	Equipment pathing and unit allocation for a process control system	700/100	Tucker, Mark et al.	☐
25	☒	US 6304791 B1	USPAT	20011016	Method for controlling semiconductor equipment interlocked with a host computer	700/121	Kim, Sung-geun	☐

Smith, Jr. et al.

US-PAT-NO: 6383402
DOCUMENT-IDENTIFIER: US 6383402 B1
TITLE: Method and apparatus for monitoring plasma processing operations
DATE-ISSUED: May 7, 2002
US-CL-CURRENT: 216/60,216/59 ,438/14 ,438/16

APPL-NO: 9/ 290903
DATE FILED: April 12, 1999
PARENT-CASE:
RELATED APPLICATIONS This patent application claims priority from and is a
continuation-in-part of Ser. No. 09/065,006, now U.S. Pat. No. 6,090,302,
filed on Apr. 23, 1998, and entitled "METHOD. AND APPARATUS FOR
MONITORING
PLASMA PROCESSING OPERATIONS."

---------- KWIC ---------

DEPR:
Yet another embodiment of a plasma health subroutine which may be used by the
plasma health module 252 is illustrated in FIG. 24. The plasma health/process
recognition subroutine 924 is generally directed to achieving an increase in
the speed of the comparison between the current plasma process being run in the
processing chamber 36 and the normal spectra subdirectory 288 by at least
initially limiting the search within the subdirectory 288 to a single plasma
process of the subdirectory 288. In this regard, personnel are allowed to
indicate which plasma process is to be run in the processing chamber 36. For
instance, the data entry device 60 for the main control unit 58 (FIG. 1) may be
used to select a plasma **recipe** to be run from a list of plasma **recipes on the
display** 130. The startup module 202 could prompt personnel to input the **recipe**
if desired through execution of step 230 of the startup routine 203 of FIG. 16.
More typically, the **recipe** to be run on a certain lot of **wafers** 18 will be
input somewhere in the **fabrication** facility (e.g., main **control** panel), and
when the chamber 36 "reads" the lot from this **wafer** 18, the plasma **recipe** which
was input in association with this lot will be automatically run.

	L #	Hits	Search Text	DBs	Tim Stamp	Type
1	L1	372549	(station OR workstation OR chamber) WITH control$4	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/04/15 15:28	BRS
2	L2	7160	L1 SAME (barcode OR bar ADJ code OR scan$4)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/04/15 15:43	BRS
3	L3	342	L2 SAME (IC OR integrated ADJ circuit OR semiconductor OR wafer OR chip)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/04/15 15:44	BRS
4	L4	6391	(station OR workstation OR interface OR chamber) SAME display$3 SAME scan$4 SAME control$4	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/04/15 15:48	BRS
5	L5	58	L3 AND L4	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/04/15 15:48	BRS
6	L6	8	("4095095" | "4833306" | "4930086" | "5325582" | "5375061" | "5432702" | "5434790" | "5537325").PN.	USPAT	2003/04/15 15:51	BRS
7	L7	20	5537325.URPN.	USPAT	2003/04/15 15:52	BRS
8	L8	12	5432702.URPN.	USPAT	2003/04/15 15:56	BRS

	S	1	Document ID	Source	Issue Date	Title	Current OR	Inventor	2	4	5
1	☒	☐	US 6136614 A	USPAT	20001024	Apparatus and method for manufacturing integrated circuit devices	438/5	Funk, Kevin K.	☒	☐	☐
2	☒	☐	US 6069911 A	USPAT	20000530	Radio network initialization method and apparatus	375/130	Sealander, Wanda et al.	☒	☐	☐
3	☒	☐	US 6027024 A	USPAT	20000222	Hand-held portable WWW access terminal with visual display panel and GUI-based WWW browser program integrated with bar code symbol reader	235/472.01	Knowles, Carl Harry	☒	☐	☐
4	☒	☐	US 5915089 A	USPAT	19990622	Supplemental data processing system for processing ply-matching data generated during multiple-part product printing	709/202	Stevens, Scott A. et al.	☒	☐	☐
5	☒	☐	US 5905251 A	USPAT	19990518	Hand-held portable WWW access terminal with visual display panel and GUI-based WWW browser program integrated with bar code symbol reader in a hand-supportable housing	235/472.01	Knowles, Carl Harry	☒	☐	☐
6	☒	☐	US 5812589 A	USPAT	19980922	Radio network initialization method and apparatus	375/141	Sealander, Wanda et al.	☒	☐	☐
7	☒	☒	US 5442561 A	USPAT	19950815	Production management system and its application method	700/100	Yoshizawa, Masahiro et al.	☐	☐	☐
8	☒	☒	US 4598459 A	USPAT	19860708	Installation for manual assemblying of components on a printed circuit board	29/564.8	Klink, Gerhard et al.	☐	☐	☐
9	☒	☒	NN8710125	IBM_T DB	19871001	DYNAMIC DATABASE			☐	☐	☐
10	☒	☒	NN9101230	IBM_T DB	19910101	Method for Automatically Printing Variable Content Labels On-line.			☐	☐	☐
11	☒	☐	US 5975740 A	USPAT	19991102	Apparatus, method and medium for enhancing the throughput of a wafer processing facility using a multi-slot cool down chamber and a priority transfer scheme	700/99	Lin, Zhihong J. et al.	☒	☐	☐
12	☒	☒	US 5651798 A	USPAT	19970729	Workpiece monitoring process using a workpiece carrier having an identification code	29/25.01	Conboy, Michael R. et al.	☐	☐	☐
13	☒	☒	US 5560775 A	USPAT	19961001	Quartz marking system	118/500	Conboy, Michael R. et al.	☐	☐	☐
14	☒	☒	US 5894172 A	USPAT	19990413	Semiconductor device with identification function	257/797	Hyozo, Masahiko et al.	☐	☐	☐
15	☒	☐	US 5079834 A	USPAT	19920114	Apparatus for and method of mounting electronic components	29/840	Itagaki, Masato et al.	☒	☐	☐
16	☒	☐	US 6052465 A	USPAT	20000418	Optical disk, an optical disk barcode forming method, an optical disk reproduction apparatus, a marking forming apparatus, a method of forming a laser marking on an optical disk, and a method of manufacturing an optical disk	369/53.21	Gotoh, Yoshiho et al.	☒	☐	☐
17	☒	☐	US 5493106 A	USPAT	19960220	Mail processing system having a barcode user interface	235/375	Hunter, Kevin D.	☒	☐	☐
18	☒	☐	US 6111637 A	USPAT	20000829	Apparatus and method for examining wafers	356/237.1	Lee, Young-Ho et al.	☒	☐	☐
19	☒	☒	US 5537325 A	USPAT	19960716	Apparatus for and method of manufacturing semiconductor wafer	700/121	Iwakiri, Eiji et al.	☐	☐	☐
20	☒	☐	US 5751581 A	USPAT	19980512	Material movement server	700/115	Tau, Lok L. et al.	☒	☐	☐

	S	1	Document ID	Source	Issue Date	Title	Curr nt OR	Inventor	2	4	5
21	☒	☐	US 5434790 A	USPAT	19950718	Versatile production system and pallet used for the system	700/110	Saka, Nobuo et al.	☒	☐	☐
22	☒	☒	US 5432702 A	USPAT	19950711	Bar code recipe selection system using workstation controllers	700/116	Barnett, Gerald W.	☐	☐	☐
23	☒	☒	US 5886896 A	USPAT	19990323	Method and apparatus for integrated control of a sensor in a manufacturing processing station	700/116	Lantz, Mikkel et al.	☐	☐	☐
24	☒	☒	US 5325582 A	USPAT	19940705	Multi-function workstation for assembly and repair of printed wiring board assemblies	29/840	Glaser, Peter S. et al.	☐	☐	☐
25	☒	☐	US 4930086 A	USPAT	19900529	Method and apparatus for sequential product processing with limited product bar code reading	700/116	Fukasawa, Yoshihito	☒	☐	☐
26	☒	☒	US 4095095 A	USPAT	19780613	Apparatus for manufacturing semiconductor devices	235/375	Muraoka, Hisashi et al.	☐	☐	☐

	L #	Hits	Search T xt	DBs	Tim Stamp	Type
1	L1	6129	(station OR workstation OR interface) SAME display$3 SAME scan$4 SAME control$4	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/04/09 15:39	BRS
2	L2	1119	L1 SAME (manufactur$3 OR fabricat$3 OR assembl$3 OR produc$4)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/04/09 17:39	BRS
3	L3	393	L2 SAME (PC OR IC OR circuit OR chip OR substrate OR wafer)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/04/09 15:49	BRS
4	L4	83	L3 AND (barcode OR bar ADJ code)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/04/09 16:45	BRS
5	L5	7	("4636634" | "4833306" | "5314564" | "5567927" | "5814829" | "5933220" | "5953579").PN.	USPAT	2003/04/09 16:41	BRS
6	L6	1	6136614.URPN.	USPAT	2003/04/09 16:23	BRS
7	L7	45	5442561.URPN.	USPAT	2003/04/09 16:33	BRS
8	L8	110	(lot OR batch) WITH (number OR code) SAME barcode	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/04/09 17:58	BRS
9	L9	5	5560775.URPN.	USPAT	2003/04/09 17:18	BRS
10	L10	2	5894172.URPN.	USPAT	2003/04/09 17:20	BRS
11	L12	13	4598459.URPN.	USPAT	2003/04/09 17:24	BRS
12	L13	4	L1 AND L8	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/04/09 17:38	BRS
13	L14	67	L8 SAME (manufactur$3 OR fabricat$3 OR assembl$3 OR produc$4)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/04/09 17:41	BRS
14	L15	41	L8 NOT (L13 OR L14)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/04/09 17:49	BRS
15	L16	17	5493106.URPN.	USPAT	2003/04/09 17:54	BRS

	L #	Hits	Search Text	DBs	Time Stamp	Typ
16	L17	5	L3 AND ((lot OR batch) WITH (number OR code))	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/04/09 17:59	BRS

	S	1	Document ID	Source	Issue Date	Title	Curr nt OR	Invent r	2
1	☒	☐	US 6136614 A	USPAT	20001024	Apparatus and method for manufacturing integrated circuit devices	438/5	Funk, Kevin K.	☒
2	☒	☐	US 6069911 A	USPAT	20000530	Radio network initialization method and apparatus *Bar code reader* *(Fig. 3)*	375/130	Sealander, Wanda et al.	☒
3	☒	☐	US 6027024 A	USPAT	20000222	Hand-held portable WWW access terminal with visual display panel and GUI-based WWW browser program integrated with bar code symbol reader	235/472.01	Knowles, Carl Harry	☒
4	☒	☐	US 5915089 A	USPAT	19990622	Supplemental data processing system for processing ply-matching data generated during multiple-part product printing	709/202	Stevens, Scott A. et al.	☒
5	☒	☐	US 5905251 A	USPAT	19990518	Hand-held portable WWW access terminal with visual display panel and GUI-based WWW browser program integrated with bar code symbol reader in a hand-supportable housing	235/472.01	Knowles, Carl Harry	☒
6	☒	☐	US 5812589 A	USPAT	19980922	Radio network initialization method and apparatus	375/141	Sealander, Wanda et al.	☒
7	☒	☒	US 5442561 A	USPAT	19950815	Production management system and its application method	700/100	Yoshizawa, Masahiro et al.	☐
8	☒	☐	US 5975740 A	USPAT	19991102	Apparatus, method and medium for enhancing the throughput of a wafer processing facility using a multi-slot cool down chamber and a priority transfer scheme	700/99	Lin, Zhihong J. et al.	☒
9	☒	☒	US 5651798 A	USPAT	19970729	Workpiece monitoring process using a workpiece carrier having an identification code	29/25.01	Conboy, Michael R. et al.	☐
10	☒	☒	US 5560775 A	USPAT	19961001	Quartz marking system	118/500	Conboy, Michael R. et al.	☐
11	☒	☒	US 5894172 A	USPAT	19990413	Semiconductor device with identification function	257/797	Hyozo, Masahiko et al.	☐
12	☒	☒	US 4598459 A	USPAT	19860708	Installation for manual assemblying of components on a printed circuit board	29/564.8	Klink, Gerhard et al.	☐
13	☒	☐	US 5079834 A	USPAT	19920114	Apparatus for and method of mounting electronic components	29/840	Itagaki, Masato et al.	☒
14	☒	☒	NN9101230	IBM_T DB	19910101	Method for Automatically Printing Variable Content Labels On-line.			☐
15	☒	☒	NN8710125	IBM_T DB	19871001	DYNAMIC DATABASE			☐
16	☒	☐	US 6052465 A	USPAT	20000418	Optical disk, an optical disk barcode forming method, an optical disk reproduction apparatus, a marking forming apparatus, a method of forming a laser marking on an optical disk, and a method of manufacturing an optical disk	369/53.21	Gotoh, Yoshiho et al.	☒

	L #	Hits	Search Text	DBs	Time Stamp	Typ
1	L7	931	wafer ADJ stepper	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/04/15 13:04	BRS
2	L8	1	resist ADJ spin ADJ track	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/04/15 13:05	BRS
3	L11	445	L7 SAME (machine OR device OR station OR workstation OR interfac$3 OR control$4)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/04/15 13:09	BRS
4	L12	319	L11 SAME (IC OR integrated ADJ circuit OR semiconductor OR chip OR photolithograph$6)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/04/15 13:12	BRS
5	L19	247	L12 SAME (manufactur$3 OR fabricat$3 OR assembl$3 OR produc$4)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/04/15 13:16	BRS
6	L20	129	L19 SAME scan$4	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/04/15 13:20	BRS
7	L21	52	L19 AND chamber	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/04/15 15:15	BRS
8	L22	2	("6466835").PN.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/04/15 14:03	IS&R
9	L23	12	("5038290" | "5093794" | "5231567" | "5237508" | "5268838" | "5280425" | "5914879" | "5928389" | "5934856" | "6078982" | "6122566" | "6336204").PN.	USPAT	2003/04/15 13:56	BRS
10	L24	26	(("4917556") or ("6024526") or ("6449523") or ("6082950") or ("5976199") or ("5955857") or ("5820679") or ("5692292") or ("5547537") or ("5536128") or ("5342460") or ("6055632") or ("4675993")).PN.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/04/15 15:15	IS&R
11	L25	19	(("6363294") or ("6348967") or ("6316045") or ("6303395") or ("6081330") or ("5812261") or ("5728222") or ("5715361") or ("5665214") or ("5536317")).PN.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/04/15 14:07	IS&R
12	L48	11	5692292.URPN.	USPAT	2003/04/15 14:40	BRS
13	L49	51	5536128.URPN.	USPAT	2003/04/15 14:44	BRS

	L #	Hits	Search Text	DBs	Time Stamp	Type
14	L50	10	5668056.URPN.	USPAT	2003/04/15 15:02	BRS

	S	1	Document ID	Source	Issue Date	Title	Current OR	Inventor	2 [1]
1	☒	☒	US 5976199 A	USPAT	19991102	Single semiconductor wafer transfer method and manufacturing system	29/25.01	Wu, Hong-Jen et al.	☒
2	☒	☐	US 5820679 A	USPAT	19981013	Fabrication system and method having inter-apparatus transporter	118/719	Yokoyama, Natsuki et al.	☒
3	☒	☒	US 5692292 A	USPAT	19971202	Transfer type circuit board fabricating system	29/740	Asai, Koichi et al.	☒
4	☒	☒	US 5536128 A	USPAT	19960716	Method and apparatus for carrying a variety of products	414/273	Shimoyashiro, Sadao et al.	☒
5	☒	☐	US 5976199 A	DERWENT	19991102	Single semiconductor wafer processing and transporting system		CHEN, I I et al.	☒
6	☒	☒	US 5536128 A	DERWENT	19960716	Carrier appts. for semiconductor device mfr. - has carriage system simultaneously carrying several types of works between several processing stations using host controller and transfer system to identify and deliver desired work		HAMADA, T et al.	☒
7	☒	☒	JP 08078882 A	DERWENT	19960322	Counter circuit substrate transfer work device - has generalisation control unit which controls individual control devices based on present condition information supplied from each individual control device		ASAI, K et al.	☒
8	☒	☐	JP 07122622 A	DERWENT	19950512	Semiconductor wafer processing with inter-apparatus transporter - moves groups of wafers around interconnected system in optimised production cycle		KAWAMOTO, Y et al.	☒

	S	1	Document ID	S urce	Issue Date	Titl	Current OR	Invent r	2
1	☒	☐	US 6336204 B1	USPAT	20020101	Method and apparatus for handling deadlocks in multiple chamber cluster tools	716/1	Jevtic, Dusan	☐
2	☒	☐	US 6122566 A	USPAT	20000919	Method and apparatus for sequencing wafers in a multiple chamber, semiconductor wafer processing system	700/218	Nguyen, Thu et al.	☐
3	☒	☐	US 6078982 A	USPAT	20000620	Pre-locking scheme for allowing consistent and concurrent workflow process execution in a workflow management system	710/200	Du, Weimin et al.	☐
4	☒	☐	US 5934856 A	USPAT	19990810	Multi-chamber treatment system	414/217	Asakawa, Teruo et al.	☐
5	☒	☐	US 5928389 A	USPAT	19990727	Method and apparatus for priority based scheduling of wafer processing within a multiple chamber semiconductor wafer processing tool	29/25.01	Jevtic, Dusan	☐
6	☒	☐	US 5914879 A	USPAT	19990622	System and method for calculating cluster tool performance metrics using a weighted configuration matrix	700/111	Wang, Qingsu et al.	☐
7	☒	☐	US 5280425 A	USPAT	19940118	Apparatus and method for production planning	712/300	Hogge, John C.	☐
8	☒	☐	US 5268838 A	USPAT	19931207	Production control system for controlling producing points	700/99	Ito, Joji	☐
9	☒	☒	US 5237508 A	USPAT	19930817	Production control system	700/100	Furukawa, Satomi et al.	☐
10	☒	☐	US 5231567 A	USPAT	19930727	Manufacturing planning system	700/100	Matoba, Hideaki et al.	☐
11	☒	☐	US 5093794 A	USPAT	19920303	Job scheduling system	700/100	Howie, George R. et al.	☐
12	☒	☐	US 5038290 A	USPAT	19910806	Managing method of a run of moving objects	701/117	Minami, Hideaki	☐